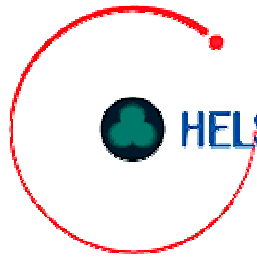


Full-size Czochralski silicon detectors irradiated with 10 MeV protons

*P. Luukka, S. Czellar, A. Heikkinen, J. Härkönen, V. Karimäki, T. Lampen, J. Nysten,
E. Tuominen, J. Tuominiemi, E. Tuovinen and L. Wendland*
Helsinki Institute of Physics, CERN/EP, Switzerland

F. Hartmann and A. Furgeri
University of Karlsruhe, Germany

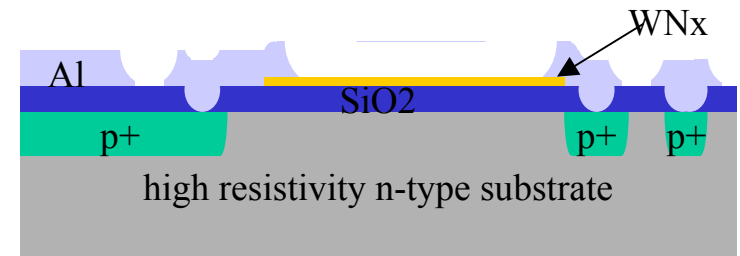
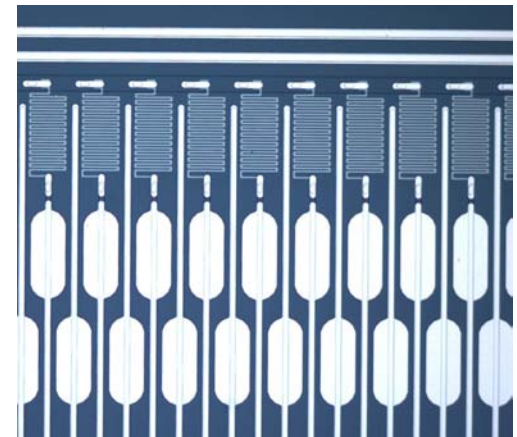
P. Laitinen, I. Riihimäki and A. Virtanen
Accelerator Laboratory, University of Jyväskylä, Finland

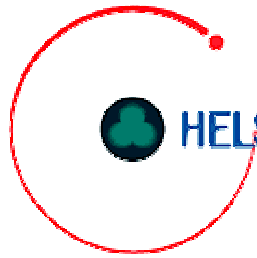


Device processing

The devices were processed at Helsinki University of Technology
Microelectronics Center

- with simple 4 level mask process:
 - 4 lithographies
 - 2 ion implantations
 - 2 thermal dry oxidations
 - 3 sputter metal depositions
- on substrate grown by magnetic Czochralski
 - nominal resistivity 900 Ωcm ,
 - thickness 380 μm ,
 - orientation $\langle 100 \rangle$,
 - oxygen concentration $\langle 10 \text{ ppma} \rangle$





Irradiations and IV- and CV-measurements

Irradiations were made at Jyväskylä University Accelerator Laboratory

- with 10 MeV protons

IV- and CV-measurements were made at University of Karlsruhe after irradiation

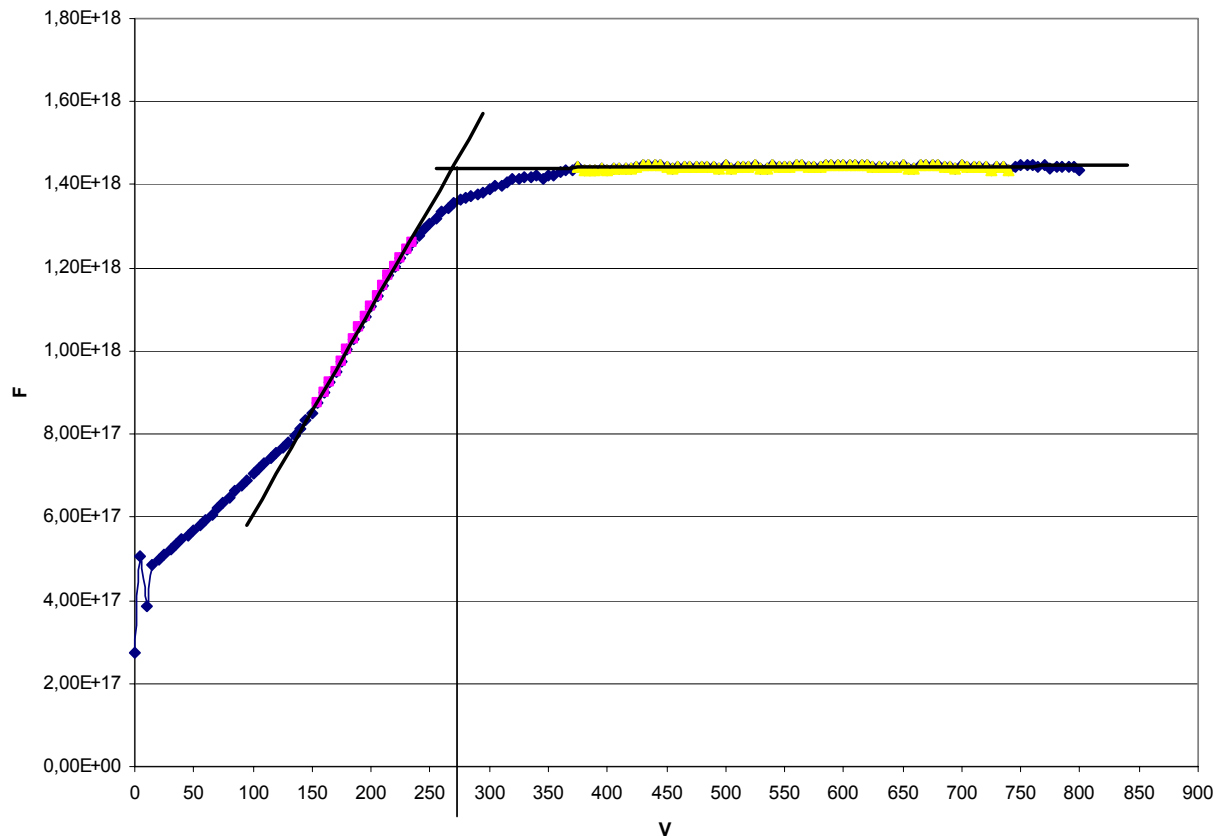
- with probestation
- @ -10°C
- guard grounded

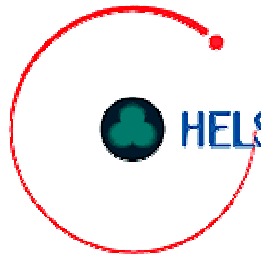




5 years of LHC $1/C^2$ curve (depl. @ 270 V)

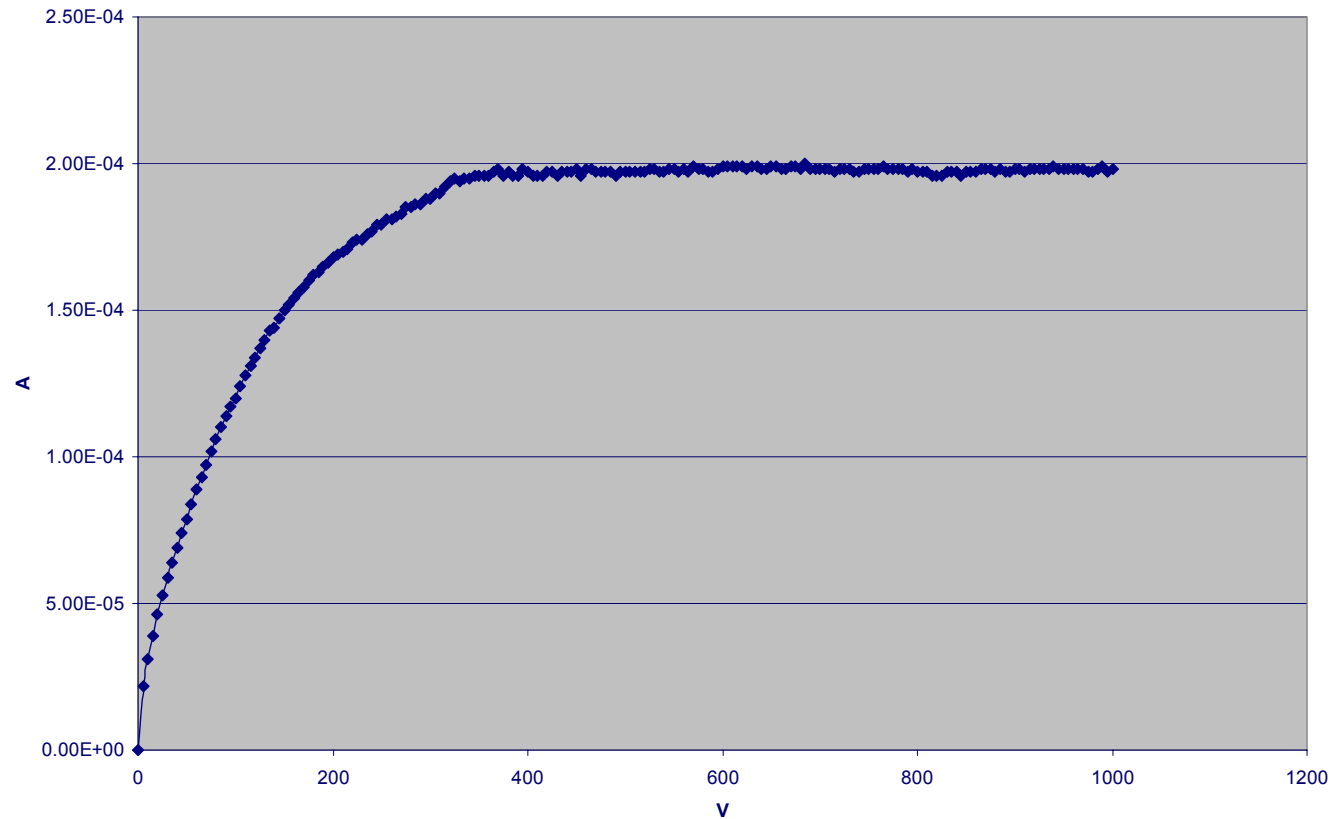
5 years of LHC $1/C^2$ step 5 V

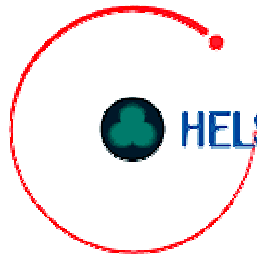




5 years of LHC leakage current

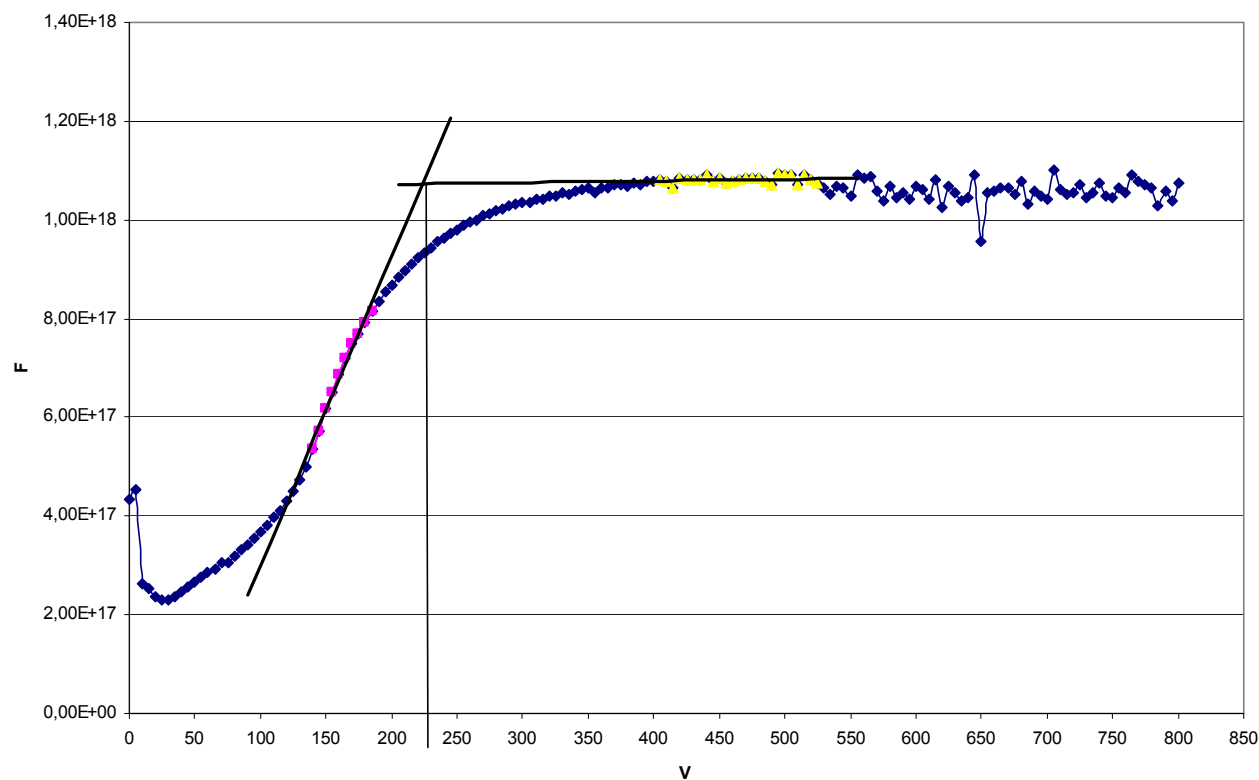
5 years of LHC IV with step 5 V

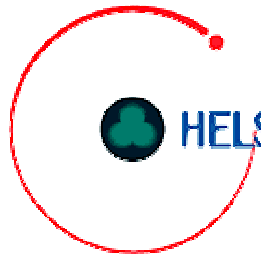




10 years LHC $1/C^2$ curve (depl. @ 225 V)

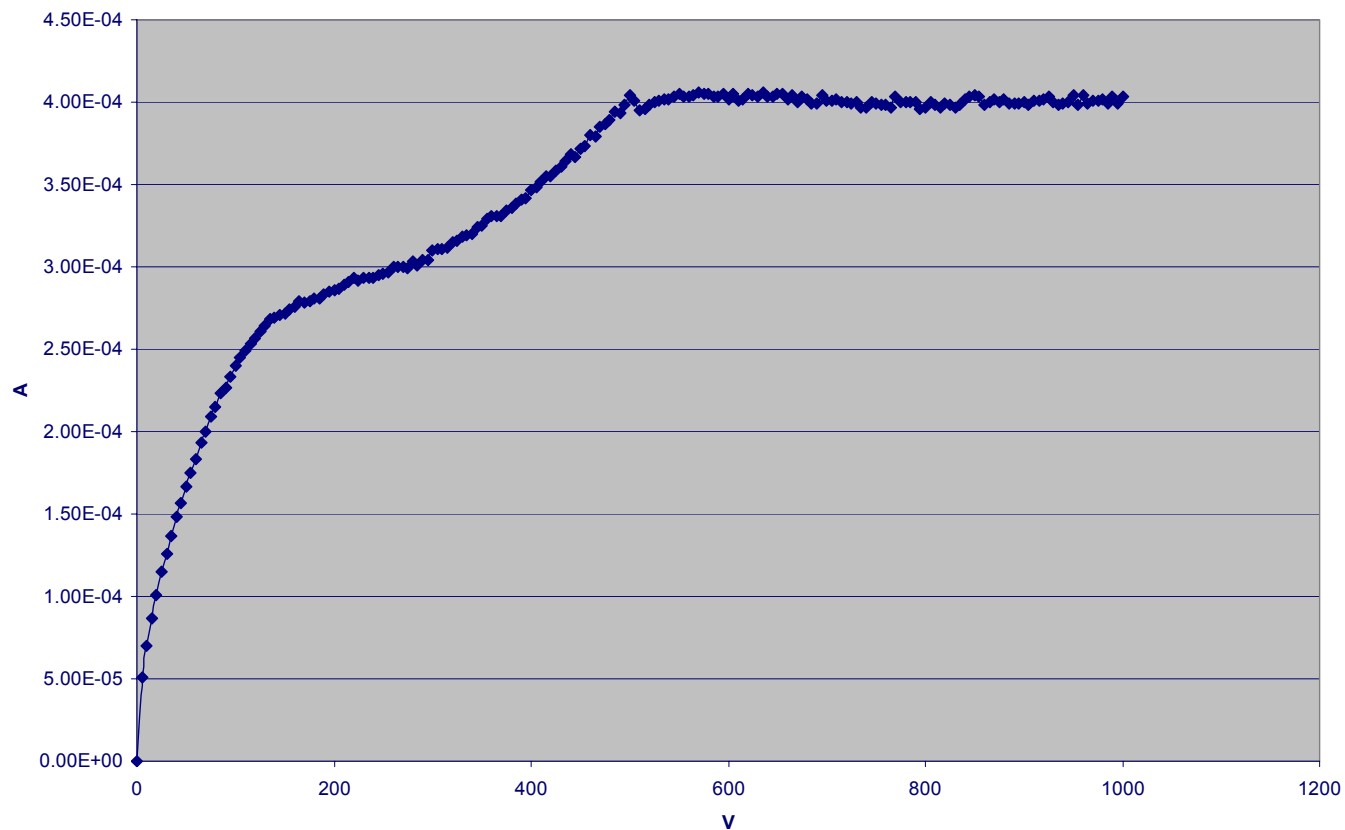
10 years of LHC $1/C^2$ with step 5 V

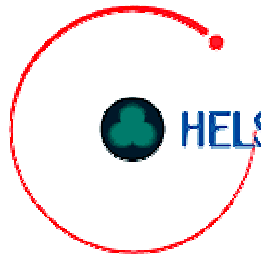




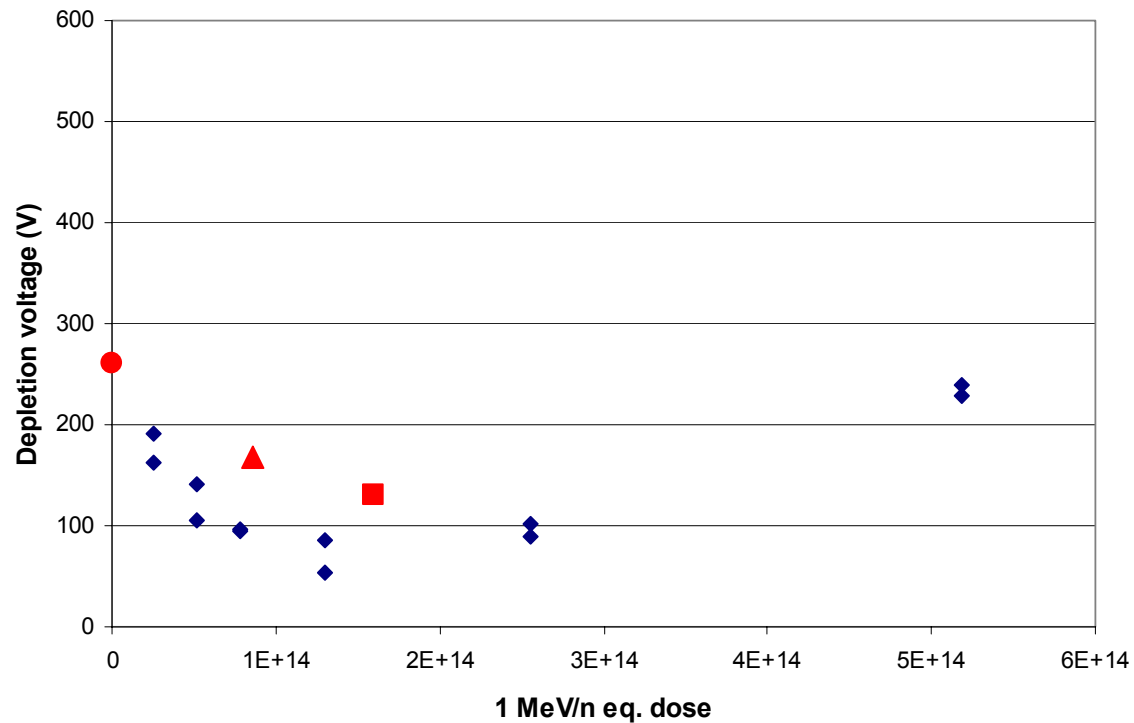
10 years of LHC leakage current

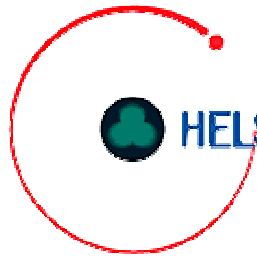
10 years of LHC IV with step 5 V





Radiation hardness of Cz-Si





Detector leakage current vs Diode I leak

Detectors @ -9,2°C

$1,9 \cdot 10^{13} \text{ p/cm}^2$ $I_{\text{leak}} \approx 183 \text{ } \mu\text{A}$

$3,8 \cdot 10^{13} \text{ p/cm}^2$ $I_{\text{leak}} \approx 261 \text{ } \mu\text{A}$

Detectors scaled to 22°C

$1,9 \cdot 10^{13} \text{ p/cm}^2$ $I_{\text{leak}} \approx 3,17 \text{ mA}$

$3,8 \cdot 10^{13} \text{ p/cm}^2$ $I_{\text{leak}} \approx 4,53 \text{ mA}$

Diodes @ 22°C

$1,9 \cdot 10^{13} \text{ p/cm}^2$ $I_{\text{leak}} \approx 43 \text{ } \mu\text{A}$

$3,8 \cdot 10^{13} \text{ p/cm}^2$ $I_{\text{leak}} \approx 66 \text{ } \mu\text{A}$

$$\frac{A_{\text{detector}}}{A_{\text{diode}}} \approx 32 \text{ cm}^2 / 0,49 \text{ cm}^2 \approx 66$$

Temperature scaling

$$I(T) = I(T_m) \left(\frac{T}{T_m} \right)^2 e^{-\frac{E_g}{k_B} \left(\frac{1}{T} - \frac{1}{T_m} \right)}$$

,where $T = 22^\circ\text{C}$ (in Kelvin's)

$T_m = -9,2^\circ\text{C}$ (in Kelvin's)

$I_{\text{leak}}(\text{detector}) / I_{\text{leak}}(\text{diode})$

$1,9 \cdot 10^{13} \text{ p/cm}^2 \approx 3170 / 43 \approx 74$

$3,8 \cdot 10^{13} \text{ p/cm}^2 \approx 4530 / 66 \approx 69$



Future measurements with Helsinki Silicon Beam Telescope at CERN H2 test beam area

SiBT:



- Eight silicon strip detectors
- Front-end electronics with VA1 chips
- PC based DAQ with commercial ADC boards
 - online monitoring and analysis
 - offline analysis after the tests

